

'97 マイクロマシン訪欧調査団

調 査 報 告 書

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## ま え が き

'97マイクロマシン訪欧調査ミッションは、第11回MEMS98の参加、MEMS主催の研究所見学エクスカージョン参加及びローマ、バルセロナ地域研究施設訪問を目的に、1998年1月24日（土）から2月5日（木）に実施されました。本報告書は上記会議の全発表論文と、訪問した研究施設の紹介を掲載しております。訪欧調査ミッションは9名の賛助企業研究者と（財）マイクロマシンセンター2名より構成されました。

MEMS98はドイツハイデルベルグ市民公会堂で1998年1月24日から1月29日まで開催され、発表件数は招待講演3件、口頭発表51件、ポスター発表63件であり、連日活発な発表と討論が繰り返されました。これらの内容は、ミッション参加メンバーにより要約され本報告書に掲載されています。なお、当会議への参加者は従来最高の670名を数えており、来年度（アメリカ オーランド）からは2セッション方式のコンフェレンスとして開催される予定です。

研究施設見学に関しては、MEMS98主催のエクスカージョンに参加し2つの研究施設、即ち、カールスルーエ研究センター及びHSG-IMITを訪問しドイツにおけるマイクロマシン技術の動向を調査しました。また、ミッション独自の研究所訪問では、これまでマイクロマシンセンターとして訪問していない地域を選択しイタリア ローマ大学、スペイン バルセロナ大学及びCNM（国立マイクロエレクトロニクスセンター）の研究施設を訪問し、研究施設の見学、研究者との技術討議、情報交換を行って南欧におけるマイクロマシン技術開発の現状を調査しました。上記、研究施設の内容については本報告書をご覧ください。

ミッションメンバーの方々には、本報告書をまとめるため多大のご協力を頂きました。ここに感謝いたします。最後に、本報告書が、皆様の今後の研究の一助となることを期待いたします。

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団長 田中 誠

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